

Abstract

The invention relates to a method for the nondestructive measurement of the thickness of thin layers with a probe (11), which has a first coil device (14) on an inner core, the geometrical centre (22) of which coil device and the geometrical centre of at least a second coil device (31) coincide, the at least second coil device (31) partially surrounding the first coil device (24), with an evaluation unit, to which signals of the coil devices (24, 31) are emitted during a measurement for ascertaining the layer thickness, characterized in that a circuit (50) is provided, by which the first and the at least second coil device (24, 31) are excited sequentially during a measurement. (Relevant figure: Figure 1)